XRD Training Notebook

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February 5, 2019 (rev. 4.1)

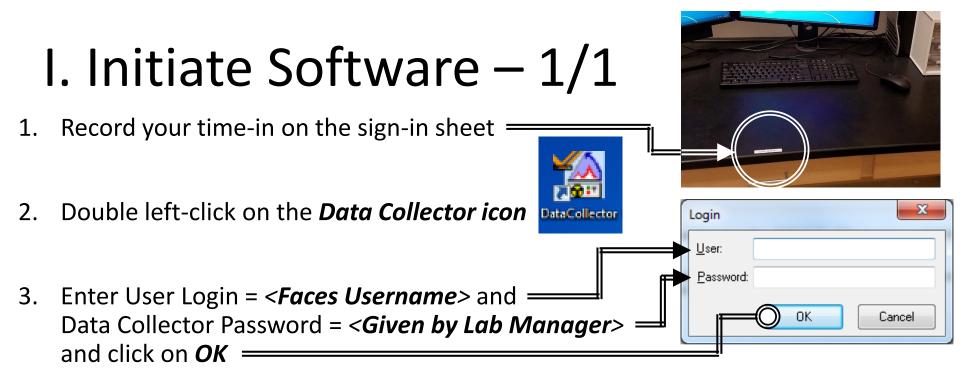
Before you begin...

- Complete the required safety training modules on UC Learning
 - Laboratory Safety Orientation (Fundamentals) 2013
 - Hazardous Waste Management
 - □ X-Ray Safety
 - Compressed Gas Safety
- Submit a copy of your Training Transcript to Lab Manager
- Review the MSE XRD Policies and Regulations
- Fill out the XRD FAU Authorization Form with PI signature
- Receive a user name and temporary password for Faces scheduling
- Arrange a time for XRD training with Lab Manager
- □ Schedule a 2 hour block on Faces for your training
- Receive a Data Collector password

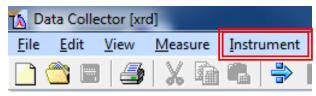
XRD Operation

- I. Initiate Software
- II. Sample Preparation
- III. Membrane Holders
- IV. Irregular Holders
- V. Round Holders
- VI. Sample Loading
- VII. XRD Cabinet
- VIII. X-Ray Settings

- IX. New Measurement Program
- X. Editing Measurement Program
- XI. Start Measurement
- XII. Data Viewing and Exporting
- XIII. Data Analysis
- XIV. Sample Unloading
- XV. Cleanup
- XVI. Troubleshoot



4. Select *Instrument -> Connect*



- 5. Select *Reflection-Transmission Spinner* and click *OK*
- 6. A dialogue box will appear, just click **OK**

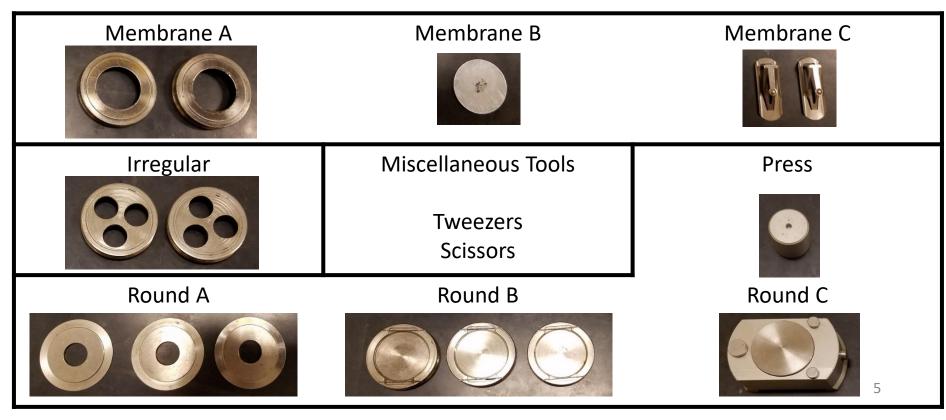
Connect				×
Configuration				ок 🔘
Name	Description	Date	Owner	Cancel
Fiat campio stage		12/4/2012	User-1	
Fiat sample stage Reflection-transmission spinner		12/4/2012	User-1	Help
literation (1997)				F

Data Collector - 9/20/2016 10:06:08 AM	
Assuming incident beam radius:240 mm Assuming Fixed divergence slit with anti-scatter slit. Assuming diffracted beam radius: 240 mm Diffracted PreFIX module. Assuming PIXcel with fixed anti-scatter slit.	OK Cancel

II. Sample Preparation – 1/2

- 1. The sample holder and preparation will vary depending on your sample
- 2. Three types of sample holders are available for use are located in the storage container
- 3. CLEAN UP AFTER EACH USE AND WIPE DOWN!





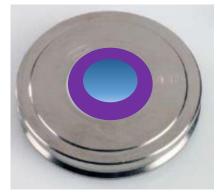
II. Sample Preparation – 2/2

- 4. It is important to always have the top of your sample at the SAME height as the top of your sample holder (no exception!)
- 5. If your sample is not at the same height as your sample holder, the peaks obtained will be incorrectly shifted away from correct positions!

Irregular

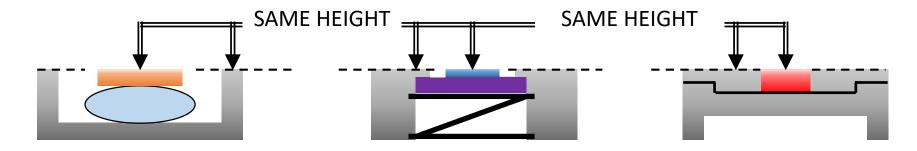


Membrane

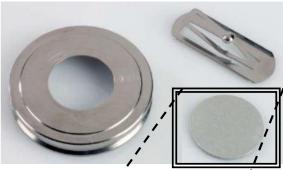








III. Membrane Holders – 1/1



1. This holder is designed for mounting:

- dust filters
- sample mounting plates
- metal plates
- pressed pellets
- silicon substrates
- 2. Requires a support plate (Diameter = 32 mm)
 - Aluminum support provided (will have background Al peaks)
 - Recommend Si Zero Background Plate
 - These need to be provided by users

MTI Corp: Zero Diffraction Plate 32 mm Dia. x 2.0 mm t, Si Crystal for XRD sample (\$150)

MTI Corp: Zero Diffraction Plate with Cavity for XRD sample: 32 Dia x 2.0 t mm with Cavity 10 ID x 0.2 mm, Si Crystal (\$199)



Warning: X-ray beam shall be 5 mm dia or less (<u>current installed beam mask is 10</u> <u>mm</u>) and hit in the center of sample when you use cavity zero diffraction plate! Otherwise the edge may result in a peak. USE AT YOUR OWN RISK!

IV. Irregular Holders – 1/1



- 1. This holder can be used to analyze solid samples with:
 - Maximum diameter = 45 mm
 - Maximum thickness = 6.5 mm
- 2. The sample can be mounted with clay available from Storehouse:



- Storehouse Description: <u>SARGENT ART 22-4096 1LB MODELING</u> <u>CLAY, WHITE (Stock #: 48702-108)</u>
- 3. Recommend using a glass slide or Si zero background plate as support for your sample on top of clay



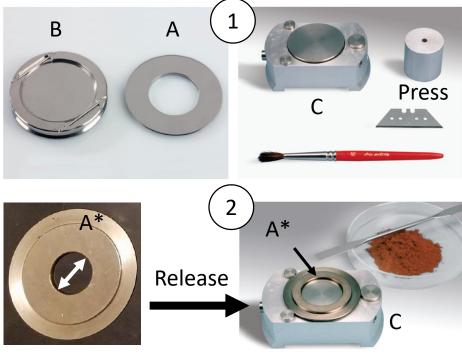
MTI Corp: Zero Diffraction Plate 32 mm Dia. x 2.0 mm t, Si Crystal for XRD sample (\$150)

MTI Corp: Zero Diffraction Plate with Cavity for XRD sample: 32 Dia x 2.0 t mm with Cavity 10 ID x 0.2 mm, Si Crystal (\$199)



Warning: X-ray beam shall be 5 mm dia or less (<u>current installed beam mask is 10</u> <u>mm</u>) and hit in the center of sample when you use cavity zero diffraction plate! Otherwise the edge may result in a peak. USE AT YOUR OWN RISK!

V. Round Holders – 1/2



Diameter = 16 mm





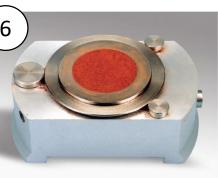
 Assemble the items for powder samples (user provides razor and brush)

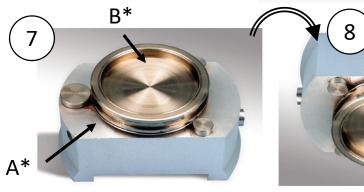
REMEMBER TO CLEAN ALL SURFACES FIRST BEFORE USING!

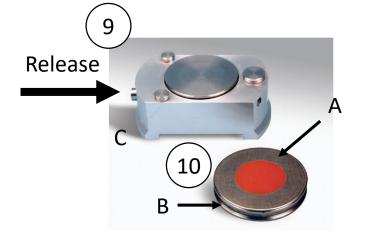
- Invert A to get A*. Place on top of C and push the release to have it sit into place.
- 3. Spread the powder into the cavity using a spatula but do not pack or compress.
- 4. Press powder with Aluminum press

V. Round Holders – 2/2







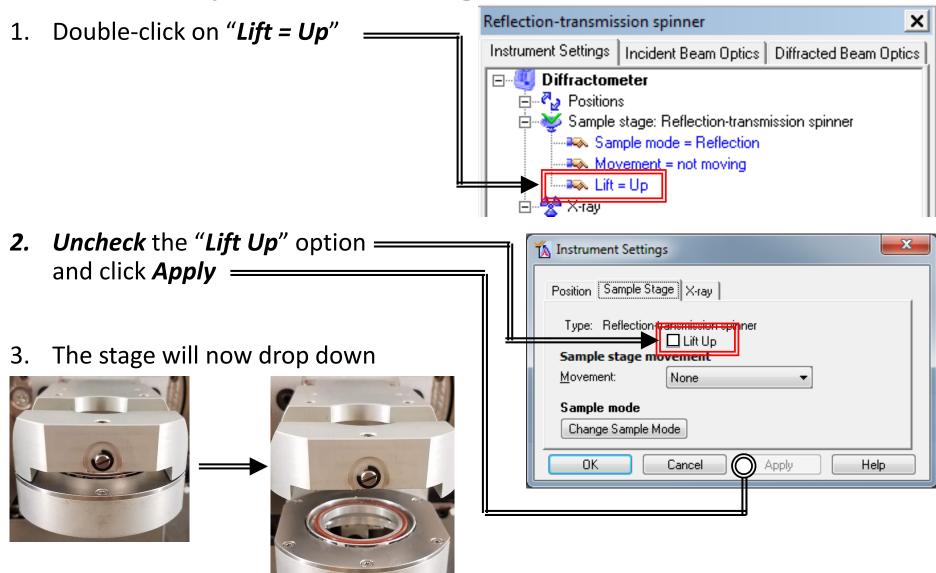


5. Remove excess powder with a straight edge or side of microscope slide

DO NOT SCRATCH TOP SURFACE!

- 6. Clean mating surfaces with small brush or provided kim wipe
- Invert B to get B* and snap on top of A*
- 8. Flip entire assembly
- 9. Push the release to remove the sample holder (A + B) from C
- 10. The surface of your sample should be smooth via back-filling approach

VI. Sample Loading – 1/4



VI. Sample Loading – 2/4

4. Press "UNLOCK DOORS" on cabinet =

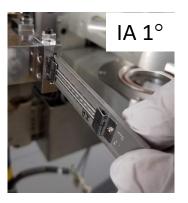
5. Open doors by pulling on the handles at the ends for better leverage _____

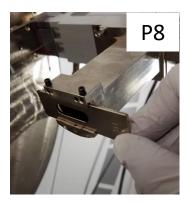




- 6. Inspect and check if desired slits are installed
 - Standard Slits are default:
 - Inc Div ½°
 - Inc Ant 1°
 - Dif Ant **P8**



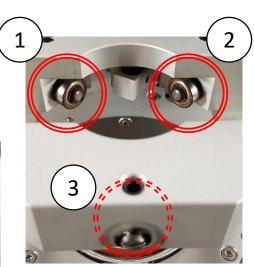




VI. Sample Loading – 3/4

- Inspect Stage for any residual sample left stuck on 3
 Spinner Bearings from previous user
- 8. Take *Kimwipe* with *IPA* and carefully wipe all *3 Spinner Bearings*
- 9. Use fresh area on *Kimwipe* to remove residual sample
- Fold, and use fresh area of *Kimwipe* to wipe down the base of the *Stage*
- 11. If necessary, use provided *Air Duster* to dry and remove any remaining dust on *Stage*









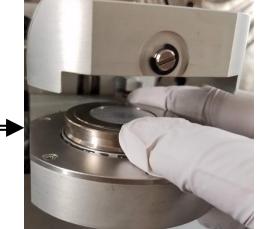
VI. Sample Loading – 4/4

12. Carefully insert *Sample Holder* into *Stage*









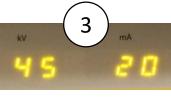
13. Confirm *Sample Holder* is properly seated into *Stage*

	🔥 Instrument Settings
14. Close doors of cabinet	Position Sample Stage X-ray
	Type: Reflection transmission spinner Image: Sample stage movement
	Movement: None -
15. Check the "Lift Up" option and click Apply	Sample mode Change Sample Mode
	OK Cancel Apply Help
16. Click <i>OK</i>	

VII. XRD Cabinet – 1/5

- Always remember to check
 3 indicators that XRD is **OK**
 - White Power Light is On
 - X-Rays On Light is On
 - X-Ray settings are 45 kV and 20 mA





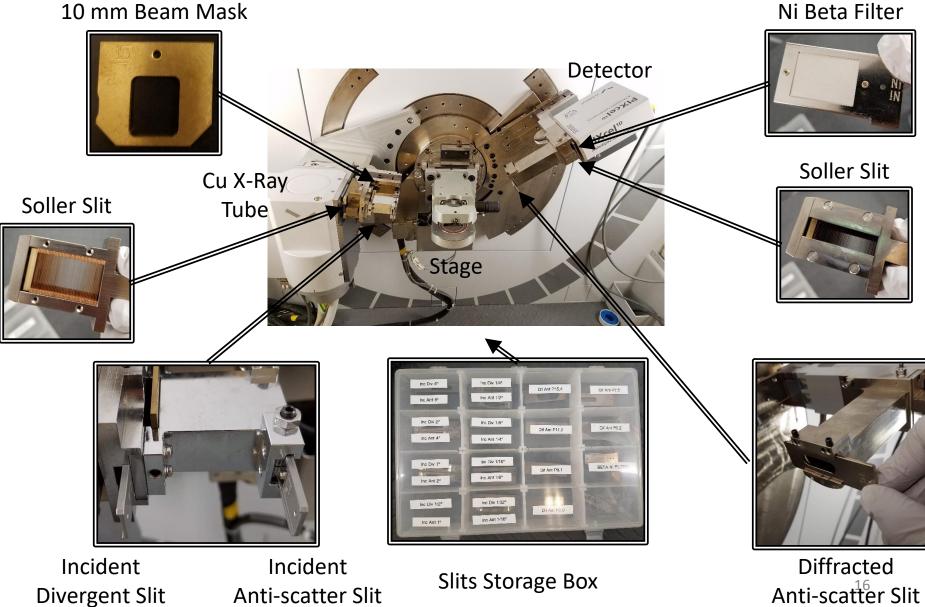
Note: If above 3 indicators are missing, contact Lab Manager



Lights On Button

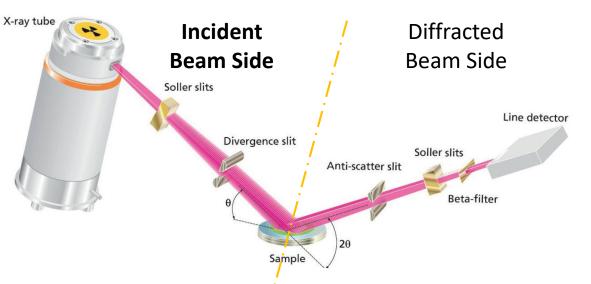
VII. XRD Cabinet – 2/5

Ni Beta Filter



VII. XRD Cabinet – 3/5

The following table describes the components for the **Incident Beam Side**

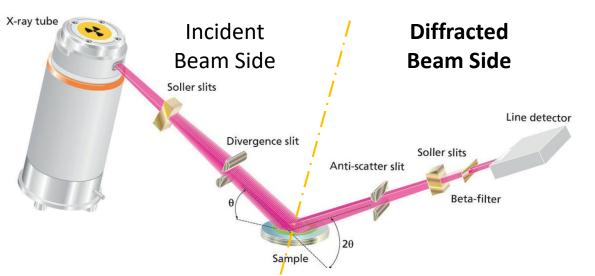


Incident Beam Side

Component Name	Function or Description
Soller Slit	Prevents axial divergence and improves peak shape and symmetry
Divergence Slit	Controls the irradiated length of the X-Ray beam on the sample. Slit size depends on sample size and starting scan angle.
Incident Anti-scatter Slit	Reduces X-Ray beam scatter and reduces background. Typically double the selection of the divergent slit.
Beam Mask (not pictured)	Controls axial width of the X-Ray beam. Match to sample size. 17

VII. XRD Cabinet – 4/5

The following table describes the components for the **Diffracted Beam Side**



Diffracted Beam Side

Component Name	Function or Description
Receiving Slit	Controls the resolution of the instrument, common setting is 0.1 mm.
Soller Slit	Match with incident selection, typically 0.04 radians.
Diffracted Anti- scatter Slit	Match to the selection of the Divergent Slit.
Beta-filter	Used to remove beta radiation.
Detector	PIXcel 1D 18

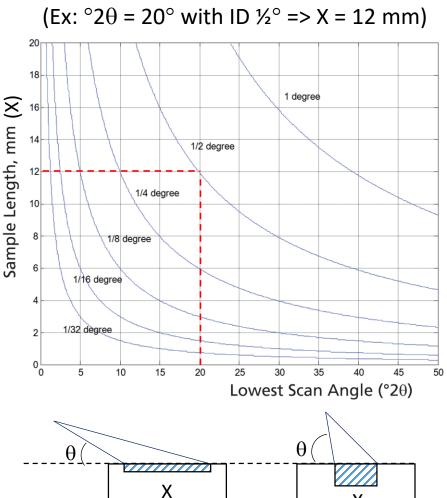
VII. XRD Cabinet – 5/5

Standard Slit Configuration = $1/2^{\circ}$, 1° , 8 mm

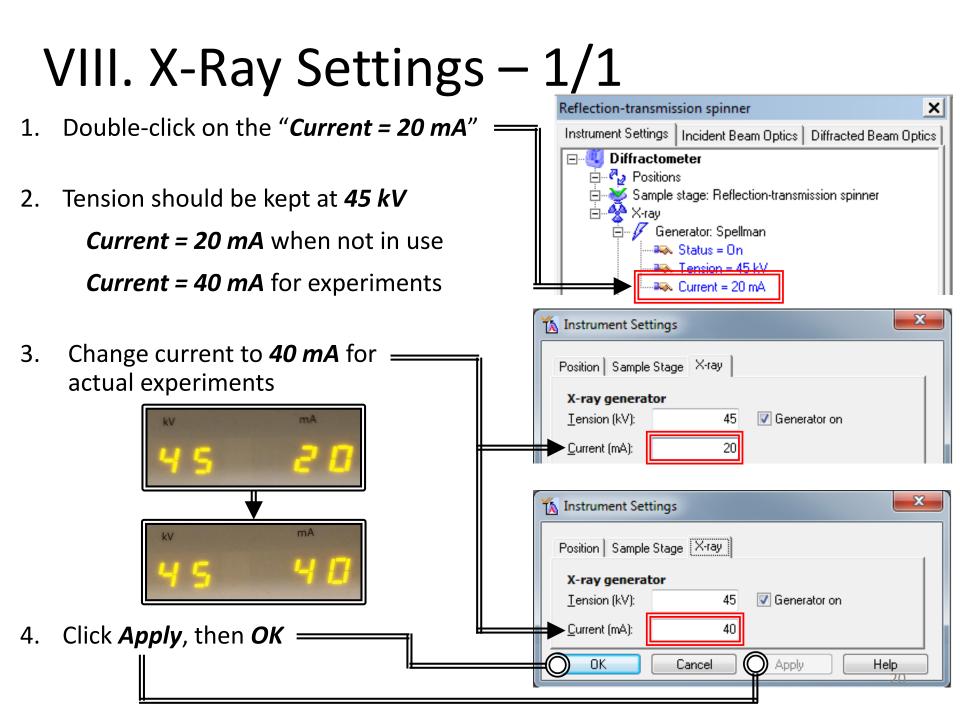
Effects of Low Scan Angles: *Irradiated Sample Length X* vs. °2θ

Slit Configurations							
Incident E	Beam Side	D iffracted Beam Side					
Incident Divergence	Incident A nti-scatter	Diffracted Anti-scatter					
ID 4°	IA 8°	P15.4	1				
ID 2°	IA 4°	P11.2					
ID 1°	IA 2°	P9.1	•				
ID 1/2°	IA 1°	P8.0					
ID 1/4°	IA 1/2°	P7.5					
ID 1/8°	IA 1/4°	P7.5					

Choose smaller slit sizes for removing background intensity at low angles

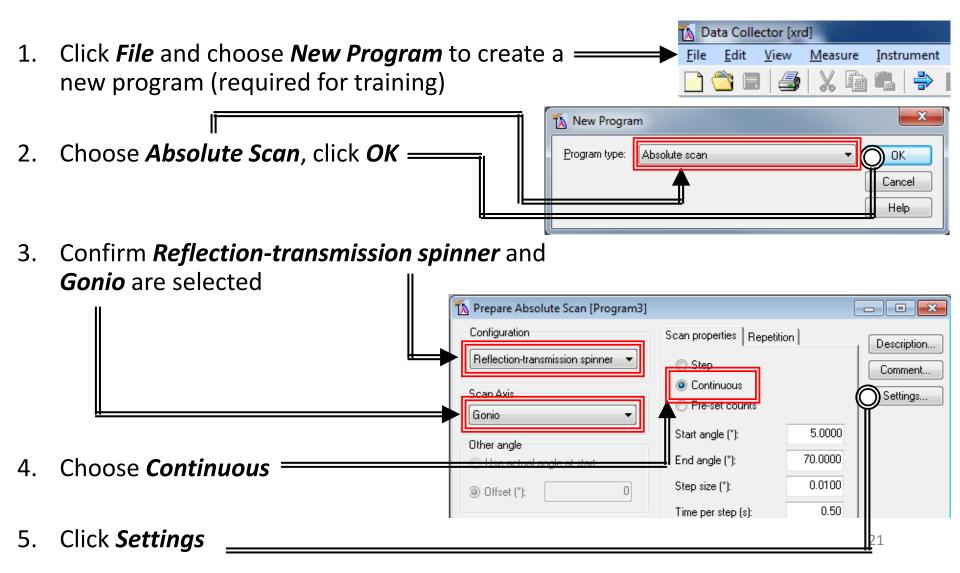


Decreasing Slit Size



IX. New Measurement Program – 1/7

Note: SKIP to X. Editing Measurement Program if you already have a program



IX. New Measurement Program – 2/7

6. Click *Movement*

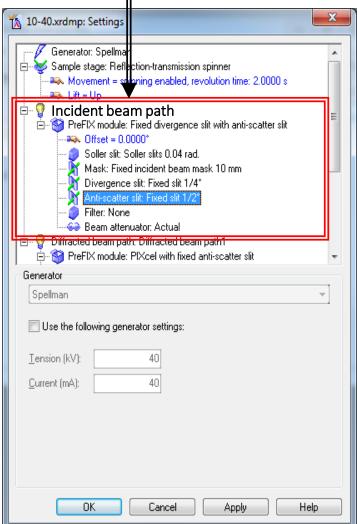
- Set to *Spinning Enabled* (recommended)
 - Set *Revolution Time = 2 seconds*
- Set to *Not moving* if homogeneity is not an issue but sample ejection is

Generator: Spellman Sample stage: Reflection-transmission spinner Movement = not moving	Generator: Spellman Sample stage: Reflection-transmission spinner Movement = spinning enabled, revolution time: 2.0000 s
ple stage movement	Sample stage movement
eflection-transmission spinner 🔹	Reflection-transmission spinner
Spinning Revolution time (s): Oscillation Not moving	 Spinning Revolution time (s): 2 Oscillation Not moving

7. The default settings show "Actual" (meaningless) for all entries

IX. New Measurement Program – 3/7

- 8. Set the following *Incident beam path* entries as follows:
 - □ PreFIX module: *Fixed divergence slit with anti-scatter slit*
 - Soller slit: Soller slits 0.04 rad
 - Mask: Fixed incident beam mask 10 mm
 - Generation Filter: None
 - Beam attenuator: *None*
 - Divergence slit: <<u>Enter what you're using</u>>; if Standard Slits then Fixed slit 1/2°
 - Anti-scatter slit: <<u>Enter what you're using</u>>; if *Standard Slits* then *Fixed slit 1°*

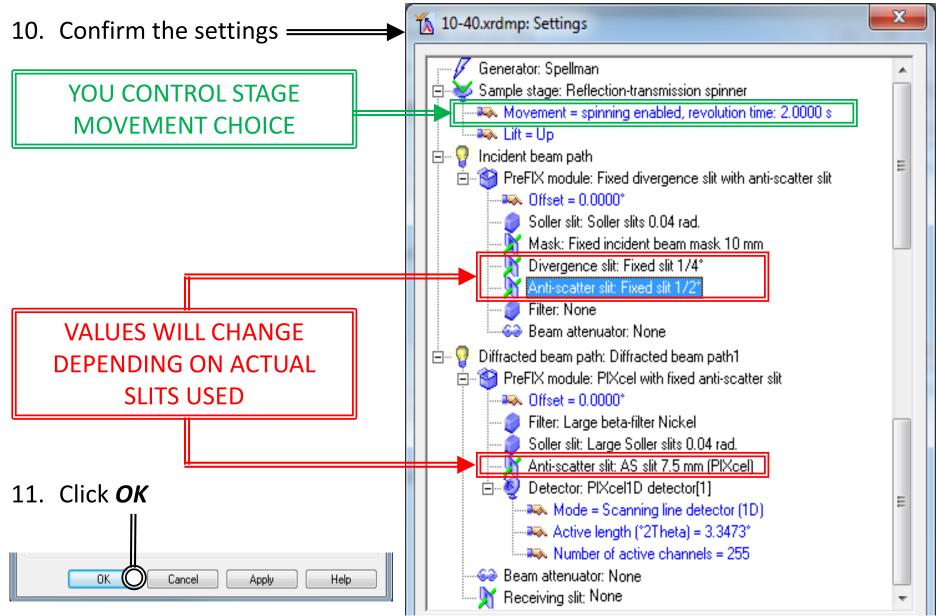


IX. New Measurement Program – 4/7

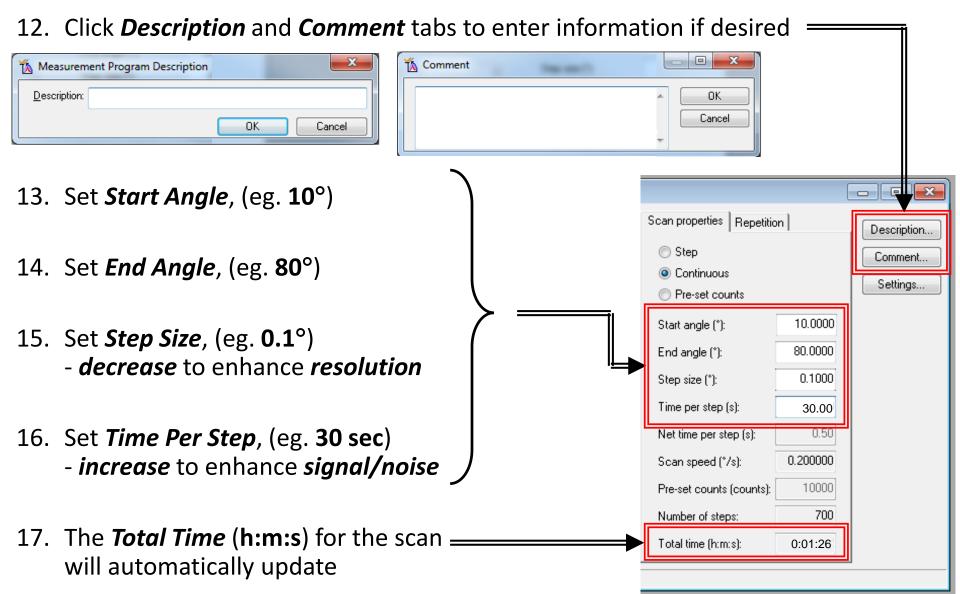
- 9. Repeat for the *Diffracted beam path* entries as follows:
 - □ PreFIX module: *PIXcel with fixed anti-scatter slit*
 - □ Filter: *Large beta-filter Nickel*
 - □ Soller slit: *Large soller slits 0.04 rad*
 - Detector: PIXcel1D detector[1]
 - Beam attenuator: None
 - Receiving slit: None
 - Anti-scatter slit: <<u>Enter what you're using</u>>; if Standard Slits then AS slit 8.0mm (PIXcel)

10-40.xrdmp: Settings	X				
Generator: Spellman Sample stage: Reflection-transmission spinner Movement = spinning enabled, revolution time: 2.0000 s					
Diffracted beam path PreFIX module: PIXcel with fixed anti-scatter slit Offset = 0.0000° Filter: Large beta-filter Nickel Soller slit: Large Soller slits 0.04 rad. Anti-scatter slit: AS slit 7.5 mm (PIXcel) Detector: PIXceI1D detector[1] Mode = Scanning line detector (1D) Active length (*2Theta) = 3.3473* Number of active channels = 255 Beam attenuator: Actual					
Generator Spellman					
Use the following generator settings: Iension (kV): 40 <u>C</u> urrent (mA): 40					
OK Cancel Apply	Help				

IX. New Measurement Program – 5/7



IX. New Measurement Program – 6/7



IX. New Measurement Program – 7/7

- 18. Click the *Close X* to close the window :
- 19. Choose to SAVE your program
- 20. Select your <**PI'S NAME**> folder

W		
🔏 Prepare Absolute Scan [Program4]		
Configuration	Scan properties Repetition	Description
Reflection-transmission spinner 💌	🔘 Step	Comment
Scan Axis	Ontinuous	Settings
	Pre-set counts	

21. Name your *Measurement Program* file

Kopen ↓ Computer →	OS (C:) PANalytical Data Collector Programs	✓ ⁴ → Search P	Programs		× P
Organize 🔻 New folder					0
☆ Favorites XRD Data	Name PANalytical Training ① 0_klee.xrdmp	Size			
File <u>n</u> ame:			e (*.xrdmp)		-
-		Open		Cancel	

- 22. Default unsorted folder is "C:\PANalytical\Data Collector\Programs"
- 23. Continue to XI. Start Measurement and SKIP X. Edit Measurement Program

X. Editing Measurement Program – 1/1

The Data Collector [xrd]

File

Measure

Instrument

The following steps are for **EDITING** existing program you already created only!

SKIP to *XI. Start Measurement* if you don't need to edit your program

- 1. Click *File* and choose *Open Program*
- Click *Browse* and find program in <*PI'S NAME*> folder in "C:\PANalytical\Data Collector\Programs"

		🏠 Open						l	x
		00	Computer 🕨 OS (C:)	 PANalytica 	I ▶ Data Collec	• * ;	Search Programs		٩
3.	Click Open	Organize	e ▼ New folder				:==	•	0
		🔶 Favo	orites RD Data	Name	· · · · · ·	Size	2		-
		JA I	File <u>n</u> ame:	JE PANal	ytical Training	•	.xrdmp file (*.xrdm	2)	-
4.	Modify desired parameters —					•	Open 🔽	Cancel	
			K Prepare Absolute Scan [f	Program4]					
5.	Click <i>Close X</i> when done		Configuration		Scan propertie	s Repe	tition	Descript	ion
			Reflection-transmission spir	nner 🔻	🔘 Step			Comme	nt
			Scan Axis		Ontinuo Pre-set o			Setting	IS
6.	Choose to SAVE your program		Gonio		Start angle (10.0000		
	, , , , ,		Other angle Use actual angle at start 		End angle (*):	80.0000		
			Offset (*):	0	Step size (*):		0.1000		
					Time per ste	p (s):	0.50		

XI. Start Measurement – 1/3

1.	Select <i>Measure -> Program</i>	ו	
			Data Collector [xrd]
2.	Click <i>Browse</i>		File Edit View Meåsure Instrument [•]
3.	Default location is "C:\PAN Collector\Programs"	alytical\Data	All
4.	Find your program in < PI'S and click Open	NAME > folder,	Name Measurement Type Created by test PC Absolute scan xrd PP au wafer Absolute scan Parawee Pumv ranytith Absolute scan xrd I Image: Scan image
			Open BrowseO Close
		[™] Open	► PANalytical ► Data Collector ► Programs ► - 4 Search Programs >
		Organize New folder	
		★ Favorites ↓ XRD Data	Name Size Size Size Size Size Size Size Siz
		File <u>n</u> ame:	.xrdmp file (*.xrdmp)

XI. Start Measurement – 2/3

- 5. \bigstar Click $_$ icon to change file location =
- 6. Default is unsorted in "*C:\XRD Data*"
- 7. Select your <**PI'S NAME**> folder
- 8. Select your *Folder* for this scan
- 9. Enter a **Name** for your scan
- 10. Confirm correct *File Folder* location
- 11. Enter a Comment, Sample ID, Sample name, or Username if desired
- 12. Clicking OK will start your scan! —

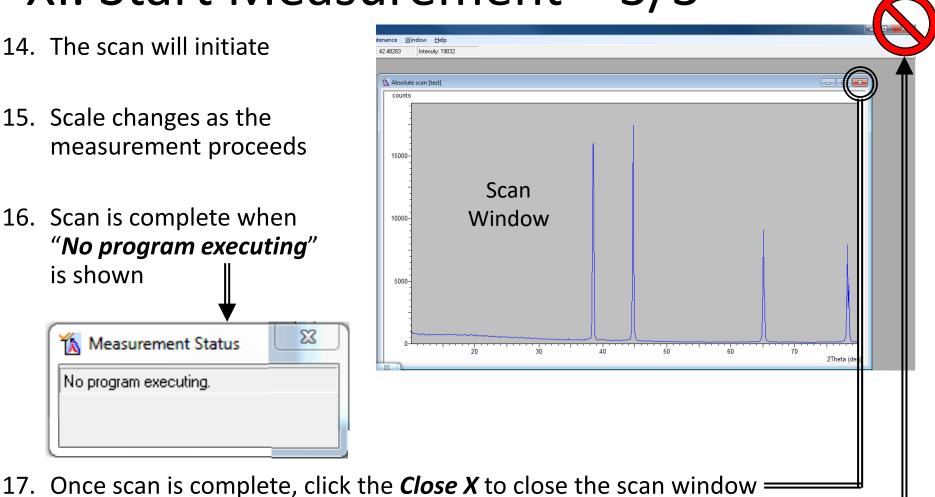
The Start				
	Program			
	Name:	C:\PANalytical\Data Colle\test PC.xrdmp Absolute scan		
	Туре:			
	Description:	test PC		
	File			
	<u>N</u> ame:	test PC_2.xrdml	REQUIRED	r El
	<u>F</u> older:	C:WRD Data		
	<u>C</u> omment:			^ +
	Sample <u>I</u> D:	OPTIONAL		
	<u>N</u> ame:			
	Prepared by:			•
OK Cancel Help				

13. If message appears, perform the actions and click on **OK**

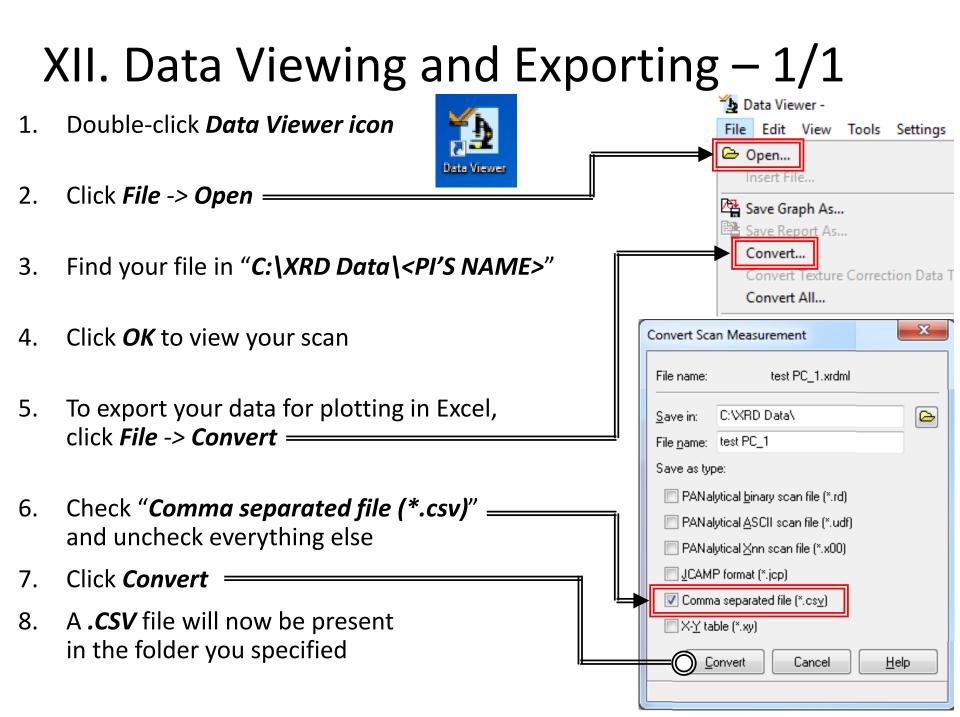
NOTE: THE MESSAGE SHOULD ONLY BE ABOUT CHECKING THAT THE COMBINATION OF SLITS YOU HAVE INDICATED IN YOUR PROGRAM ARE INSTALLED

XI. Start Measurement – 3/3

- 14. The scan will initiate
- 15. Scale changes as the measurement proceeds
- 16. Scan is complete when "No program executing" is shown 23 🔨 Measurement Status No program executing.



18. DO NOT CLOSE THE DATACOLLECTOR WINDOW



XIII. Data Analysis – 1/1

NOTE: High Score can only be used on "High Score" computer outside

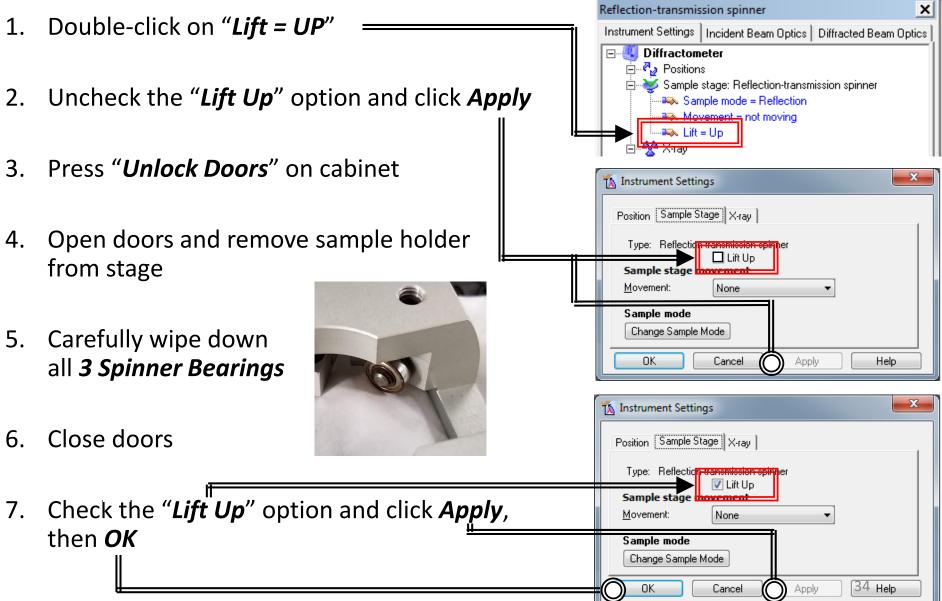
 If you plan on using *High Score*, transfer your files directly to computer outside by transferring them to the "Z" drive directory (computers are networked) or use a flash drive

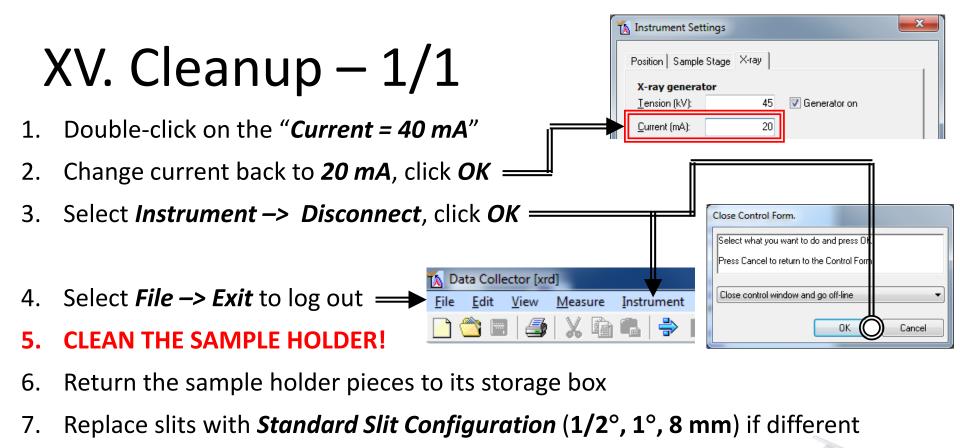




- 2. Refer to "*Introduction to PANalytical X'Pert HighScore Plus v3.0*" guide by Scott A. Speakman available on desktop of "High Score" computer
- 3. Guide is also available on MSE XRD website under Useful Documentation: http://www.mse.ucr.edu/facilities_xrd.html

XIV. Sample Unloading – 1/1

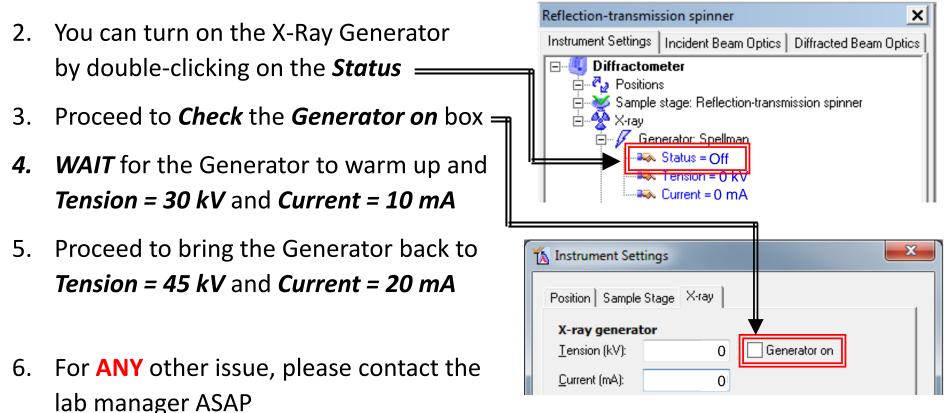




- 8. Return any other used slits back to its storage box
- 9. Brush up any sample that may have dropped into the cabinet
- 10. Turn OFF the lights to the cabinet (if ON)
- 11. Close doors (if open)
- 12. Record your **time-out** on the **sign-in sheet**, slits used, and any issues encountered like dirty sample holders or instrument errors

XVI. Troubleshoot – 1/1

1. If XRD is powered **ON** but with **Tension = 0 kV** and **Current = 0 mA** ...



- Call the lab manager at (951) 827-3378
- E-mail the lab manager (Perry: pcheung@ucr.edu)
- Stop by the lab manager's office at MSE 311